

(总公司)上海大族富创得科技股份有限公司 (HEAD OFFICE) SHANGHAI FORTREND TECHNOLOGY CO.,LTD

无锡富创得精密设备有限公司

WUXI FORTREND PRECISION EQUIPMENT CO.,LTD

电话(Tel): 021-34786180

网址(Web): http://www.fortrendpe.com 邮箱(E-mail):zhengqbfcd307@fortrend.com.cn 地址(Add):无锡市新吴区梅村街道梅育路100号

Address: 100 Meiyu Road, Meicun Street, Xinwu District, Wuxi City





微信公众号

官方网站

经销商 Distributors

英国 UK

Sistem Technology

Address: Grafton Suite, Caswell Science & Technology Park, Towcester, Northants, NN12 8EQ, UK

Tel: (44) 1327 317621

韩国 South Korea

SD Solution

Address: #509,Biz-tower,63-12,Dongtancheomdansaneop 1-ro,Hwaseong-si,Gyeonggi-do,Republic of korea

Tel: (81) 42-468-4164

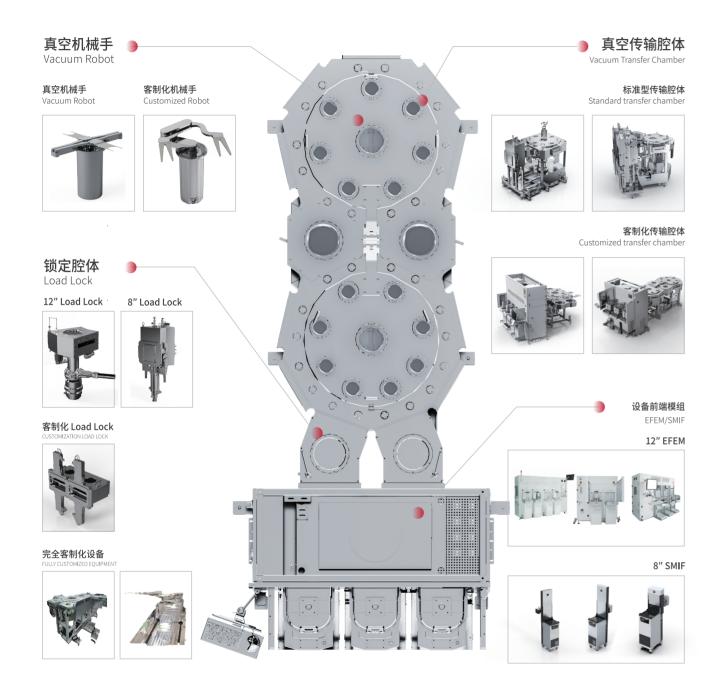
*本册展示产品图片为示意图,文内技术参数及图片可能会因为改良、升级等与实际产品有所差异,仅供参考,详细信息请向您的客户经理确认,如有变动恕不另行通知。

The product pictures shown in this volume are rendered or taken. The technical parameters and pictures may be different from the actual products due to improvement and upgrade, etc., for reference only. Please confirm with your account manager for details.

无锡富创得精密设备有限公司

WUXI FORTREND PRECISION EQUIPMENT CO.,LTD





客制化方案 CUSTOMIZED SOLUTIONS

■ 设备前端可选配EFEM / SMIF,EFEM可提供标准型与客制型

 $\label{thm:equipment} {\sf EFEM/SMIF}\ can be optionally equipped at the equipment front end, with {\sf EFEM}\ offering standard and custom types.$

■ Load Lock可选不同结构与传输方式

Load Lock can be chosen with different structures and transfer methods.

■可根据实际工艺腔要求制作客制化传输腔体

Customized transfer chambers can be made according to actual process chamber requirements.

■ 真空机械手可根据实际工况选择不同型号与末端执行器

Vacuum mechanical arms can be selected with different models and end effectors according to actual operating conditions.

■ 传输腔体与Load Lock可选内置的定向 / 冷却/ 预热模组

Transfer chambers & Load Lock can include optional built-in directional / cooling / pre-heating modules.

■ 可选配的AWC功能、Buffer 功能、晶圆存储模组

Optional features include AWC functionality, Buffer functionality, wafer storage modules.



客户信息 CUSTOM INFO.				
公司名称 Company name		地址 Company Add.		
对接人 Contact person		职务 Postition		
电话 Phone number		邮箱 E-mali		

			需求配置表 QUIREMENTS CONFIG.		
工艺设备类型 Process equipment type		□ PVD □ CVD □ AL	D □ EBL □ 刻蚀 Etch □其他 Other		
晶圆&载具规格 Wafer & Carrier Spec.		晶圆尺寸 Wafer Size	□ 150mm(6 ") □ 200mm(8 ") □ 300mm(12 ") □ 其他 Othermm		
		晶圆类型 Wafer Type	□ 普通 Normalµm □ TAIKOµm □ 其他 Other pg Thicknessµm		
		晶圆材质 Wafer Material	□ 単晶硅 Si □ 碳化硅 SiC □ 玻璃 Glass □ 其他 Otherμm		
		载具类型 Carrier Type	□ FOUP/FOSB (SEMI) □SMIF POD □Open Cassette □其他 Other		
		载具规格 Carrier Spec.	生产商 Maker型号 Model		
		载具供应方法 Carrier Feeding	人工 Operator		
传输模组规格 Transfer Moudle Spec.	主设备 Primary Equipment	洁净度 Cleanness	□ ISO - Class 3 □ 其他 Other		
		对接工艺腔数量 Docking PM Qty.	□1 □3 □4 □其他 Other		
		对接 Load Lock 数量 Docking Load Lock Qty.	□ 1 □ 2 □ 其他 Other		
		前端设备 end Equipment	□ EFEM □ SMIF □ 不选配 None-opention □ 其他 Other		
备注事项 Note					
			请在您的客户经理协助下填写此表格 Please fill out this form with the assistance of your account manager.		













深耕半导体领域多年,适配多数前道工艺设备

requirements.

Deeply rooted in the semiconductor field for many years, adaptable to most semiconductor front-end process equipment.

富创得深耕半导体传输领域四十余年,设备适配半导体前道工艺多数制程。所有量产设 备均符合SEMI标准,适配各种晶圆/掩膜等半导体/泛半导体物料工艺设备的工况需求。 Fortrend has been deeply involved in the semiconductor transport field for over forty years, with equipment adapted to most semiconductor front-end processes. All production equipment complies with SEMI standards and adapts to the process requirements of various semiconductor/microelectronic material processing equipment, such as wafers/masks.

Quadrilateral Wafer Vacuum Transfer Platform

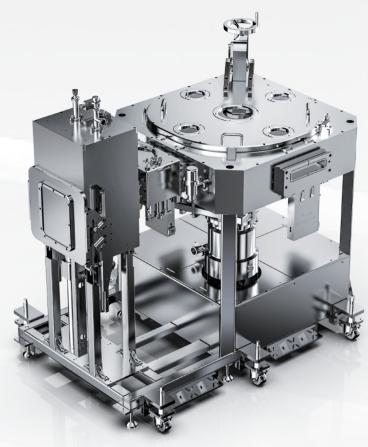
提供标准化模块与客制化方案,满足不同需求 适用于 SUITABLE FOR Providing standardized modules and customized solutions to meet different

真空传输系统可提供标准方案供制程设备进行对接,也可根据客户要求进行设备的客 制化,软硬件均有成熟方案可供选择,满足不同的制程设备与实际工况的需求。

Fortrend vacuum transfer systems can provide standard solutions for process equipment integration and can also be customized according to customer requirements. Both software and hardware have mature solutions to choose from, meeting the needs of different process equipment and actual operating conditions.







四边形晶圆真空传输平台

■ 150mm,200mm晶圆(含TAIKO、Frame晶圆)、掩膜、泛半导体物料(光伏硅板等)

Wafers up to 200mm (including TAIkO, Frame wafers), masks, and general semiconductor materials (such as photovoltaic silicon wafers, etc.)

■ PVD、CVD、ALD等半导体前道/泛半导体工艺设备

PVD, CVD, ALD, and other semiconductor front-end / general semiconductor process equipment

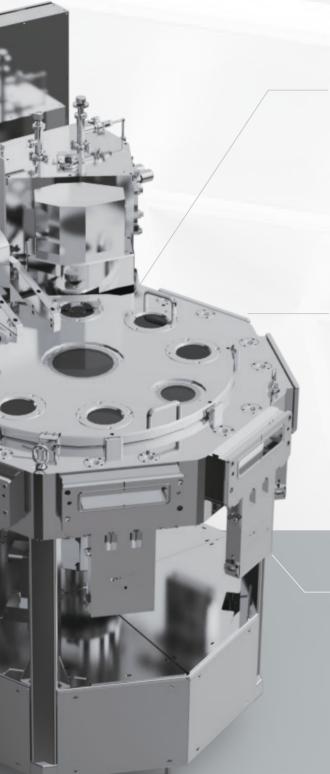
■ 高洁净度传输,晶圆传输洁净度Class1

High cleanliness transmission, wafer surface cleanliness Class 1

■ 高效率, 高稳定性传输, 传输效率 > 200 pcs/h; Up time: > 98%

Efficient and stable transmission, with a transmission efficiency of ≥ 200 pcs/h; Up time: ≥98%

■ 支持国产化替代,客户化定制



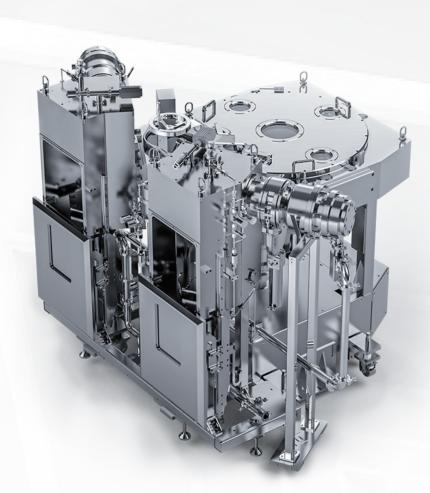




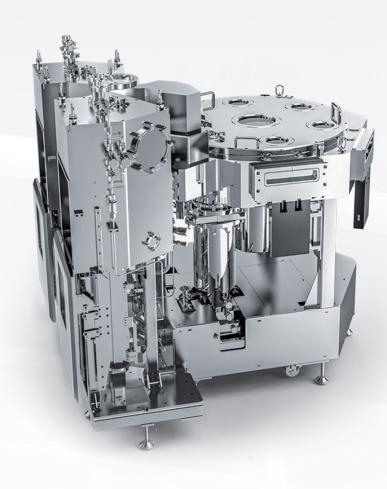
PENTAGONAL STANDARD VACUUM TRANSFER SYSTEM











五边形晶圆真空传输平台

PENTAGON WAFER VACUUM TRANSFER PLATFORM

适用于 SUITABLE FOR

■ 150mm,200mm晶圆(含TAIKO、Frame晶圆)、掩膜、泛半导体物料(光伏硅板等)

Wafers up to 200mm (including TAIkO, Frame wafers), masks, and general semiconductor materials (such as photovoltaic silicon wafers, etc)

■ PVD、CVD、ALD等半导体前道/泛半导体工艺设备

PVD, CVD, ALD, and other semiconductor front-end / general semiconductor process equipment

■ 高洁净度传输,晶圆传输洁净度Class1

High cleanliness transmission, wafer surface cleanliness Class 1

■ 高效率, 高稳定性传输, 传输效率 ≥ 200 pcs/h; Up time: ≥ 98%

Efficient and stable transmission, with a transmission efficiency of ≥ 200 pcs/h; Up time: ≥98%

■ 支持国产化替代,客户化定制

Support localization substitution and customized customization

六边形晶圆真空传输平台

HEXAGON WAFER VACUUM TRANSFER PLATFORM

适用于 SUITABLE FOR

■ 150mm,200mm晶圆(含TAIKO、Frame晶圆)、掩膜、泛半导体物料(光伏硅板等)

Wafers up to 200mm (including TAIkO, Frame wafers), masks, and general semiconductor materials (such as photovoltaic silicon wafers, etc.)

■ PVD、CVD、ALD等半导体前道/泛半导体工艺设备

PVD, CVD, ALD, and other semiconductor front-end / general semiconductor process equipment

■ 高洁净度传输,晶圆传输洁净度Class1

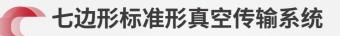
High cleanliness transmission, wafer surface cleanliness Class 1

■ 高效率, 高稳定性传输, 传输效率 > 200 pcs/h; Up time: > 98%

Efficient and stable transmission, with a transmission efficiency of ≥ 200 pcs/h; Up time: ≥98%

■ 支持国产化替代,客户化定制



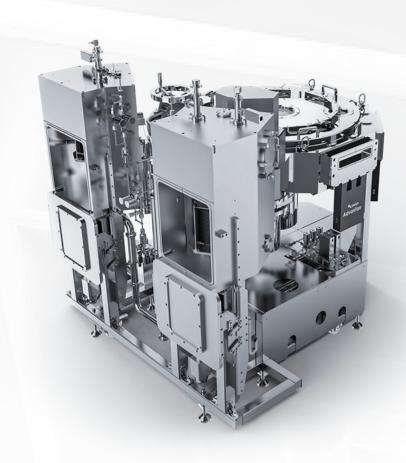


HEPTAGON STANDARD VACUUM TRANSFER SYSTEM









七边形晶圆真空传输平台

HEPTAGON WAFER VACUUM TRANSFER PLATFORM

适用于 SUITABLE FOR

■ 150mm,200mm晶圆(含TAIKO、Frame晶圆)、掩膜、泛半导体物料(光伏硅板等)

Wafers up to 200mm (including TAIkO, Frame wafers), masks, and general semiconductor materials (such as photovoltaic silicon wafers, etc.)

■ PVD、CVD、ALD等半导体前道/泛半导体工艺设备

PVD, CVD, ALD, and other semiconductor front-end / general semiconductor process equipment

■ 高洁净度传输,晶圆传输洁净度Class1

High cleanliness transmission, wafer surface cleanliness Class 1

■ 高效率, 高稳定性传输, 传输效率 ≥ 200 pcs/h; Up time: ≥ 98%

Efficient and stable transmission, with a transmission efficiency of ≥ 200 pcs/h; Up time:≥98%

■ 支持国产化替代,客户化定制

Support localization substitution and customized customization

八边形晶圆真空传输平台

OCTAGON WAFER VACUUM TRANSFER PLATFORM

适用于 SUITABLE FOR

■ 150mm,200mm晶圆(含TAIKO、Frame晶圆)、掩膜、泛半导体物料(光伏硅板等)

Wafers up to 200mm (including TAIkO, Frame wafers), masks, and general semiconductor materials (such as photovoltaic silicon wafers, etc.)

■ PVD、CVD、ALD等半导体前道/泛半导体工艺设备

PVD, CVD, ALD, and other semiconductor front-end / general semiconductor process equipment

■ 高洁净度传输,晶圆传输洁净度Class1

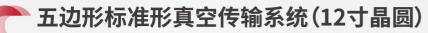
High cleanliness transmission, wafer surface cleanliness Class 1

■ 高效率, 高稳定性传输, 传输效率 ≥ 200 pcs/h; Up time: ≥ 98%

Efficient and stable transmission, with a transmission efficiency of ≥ 200 pcs/h; Up time:≥98%

■ 支持国产化替代,客户化定制

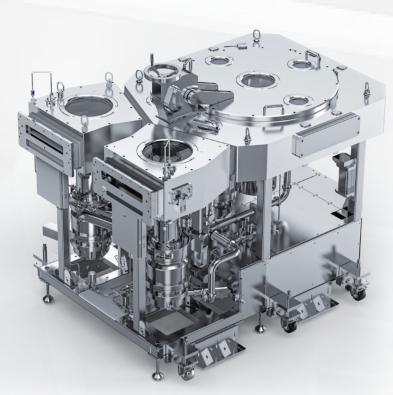




PENTAGONAL STANDARD VACUUM TRANSFER SYSTEM (12-INCH WAFER)

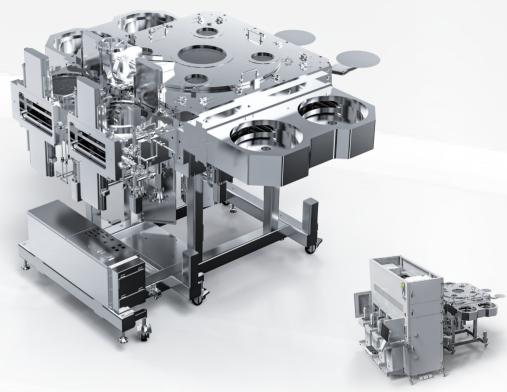








客制化-五边形标准形 真空传输系统(12寸晶圆)



客制化—12寸 双入料VTM

五边形标准形真空传输系统(12寸晶圆)

PENTAGONAL STANDARD VACUUM TRANSFER SYSTEM (12-INCH WAFER)

适用于 SUITABLE FOR

■ 300mm晶圆(含TAIKO、Frame晶圆)、掩膜、泛半导体物料(光伏硅板等)

Wafers up to 300mm (including TAIkO, Frame wafers), masks, and general semiconductor materials (such as photovoltaic silicon wafers, etc.)

■ PVD、CVD、ALD等半导体前道/泛半导体工艺设备

PVD, CVD, ALD, and other semiconductor front-end / general semiconductor process equipment

■ 高洁净度传输,晶圆传输洁净度Class1

High cleanliness transmission, wafer surface cleanliness Class 1

■ 高效率, 高稳定性传输, 传输效率 ≥ 200 pcs/h; Up time: ≥ 98%

Efficient and stable transmission, with a transmission efficiency of ≥ 200 pcs/h; Up time: ≥98%

■ 支持国产化替代,客户化定制

Support localization substitution and customized customization

晶圆双入料真空传输平台

DUAL-FEED WAFER VACUUM TRANSFER PLATFORM

适用于 SUITABLE FOR

■ 300mm晶圆(含TAIKO、Frame晶圆)、掩膜、泛半导体物料(光伏硅板等)

Wafers up to 300mm (including TAIkO, Frame wafers), masks, and general semiconductor materials (such as photovoltaic silicon wafers, etc.)

■ PVD、CVD、ALD等半导体前道/泛半导体工艺设备

PVD, CVD, ALD, and other semiconductor front-end / general semiconductor process equipment

■ 高洁净度传输,晶圆传输洁净度Class1

High cleanliness transmission, wafer surface cleanliness Class 1

■ 高效率, 高稳定性传输, 传输效率 ≥ 200 pcs/h; Up time: ≥ 98%

Efficient and stable transmission, with a transmission efficiency of \geq 200 pcs/h; Up time: \geq 98%

■ 支持国产化替代,客户化定制